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INFORMATION DISCLOSURE STATEMENT		**Applicants:** Shunpei YAMAZAKI et al.	
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Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date (if appropriate)
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Examiner	Date Considered 6/9/03

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this formwith next communication to applicant.